

LITHOGRAPHIC APPARATUS**ABSTRACT**

5 A lithographic projection apparatus is provided with an optical system built into the
wafer table for producing an image of a wafer mark that is provided on the back side of the
wafer. The image is located at the plane of the front side of the wafer and can be viewed by an
alignment system from the front side of the wafer. Simultaneous alignment between marks on
the back and front of the wafer and a mask can be performed using a pre-existing alignment
10 system

20043271.014192